



<b>Form 1449 (Modified)</b>  <b>Information Disclosure</b> <b>Statement By Applicant</b>  (Use Several Sheets if Necessary)	Attorney Docket No: U.S. LAM2P246 09/821,415
	Applicant: Gotkis et al.
	Filing Date: March 28, 2001
	Group: 2811

### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
<u>V<sub>h</sub></u>	A	5,034,799	07/1991	Tomita et al.	357	71
<u>V<sub>h</sub></u>	B	5,828,121	10/1998	Lur et al.	257	522
<u>V<sub>h</sub></u>	C	6,057,224	05/2000	Bothra et al.	438	619
	D					
	E					
	F					
	G					
	H					
	I					
	J					
	K					

### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
<u>V<sub>h</sub></u>	L	EP0872887A2	21/10/1998	EPO	H01L	23/48		X
<u>V<sub>h</sub></u>	M	63-313896 (and English Abstract)	12/21/1988	JPO	H05K	3/46	X	
	N							
	O							
	P							

### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
<u>V<sub>h</sub></u>	R	Zielinski et al., "Damascene Integration of Copper and Ultra-Low-k Xerogel for High Performance Interconnects", p. 31.7.1 to 31.7.3, IEDM 1997, Texas Instruments, Dallas, TX.
Examiner <u>HUNG NU</u>		Date Considered <u>05/23/05</u>

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.